



Docket No.: 296428US26PCT



COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

ATTORNEYS AT LAW

RE: Application Serial No.: 10/593,254  
Applicants: Tsuyoshi TAKAHASHI, et al.  
Filing Date: September 18, 2006  
For: METHOD AND APPARATUS FOR FORMING METAL SILICATE  
FILM, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE  
Group Art Unit: 1792  
Examiner: MILLER, JR, J.A.

SIR:

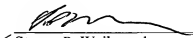
Attached hereto for filing are the following papers:

**RESPONSE TO RESTRICTION REQUIREMENT**

Credit card payment is being made online (if electronically filed), or is attached hereto (if paper filed), in the amount of **\$0.00** to cover any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. **15-0030**. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

  
Steven P. Weihrouch

Registration No. 32,829

Customer Number

**22850**

(703) 413-3000 (phone)  
(703) 413-2220 (fax)  
(OSMMN 10/08)

Michael L. Gellner  
Registration No. 27,256